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|-----------------------------------|--|---------------------------|---|-------------|
| <b>Notice of References Cited</b> |  | Application/Control No.   | Applicant(s)/Patent Under Reexamination<br>09/903,480<br>OKADA ET AL. |             |
|                                   |  | Examiner<br>Ayal I Sharon | Art Unit<br>2123  | Page 1 of 2 |

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